



Title:

Method of Forming Oxide Regions Over Semiconductor Substrates

Assignee:

Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

References - See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. No admission is made regarding whether any of the submitted references is prior art. Copies of the references are attached.

Respectfully submitted,

Attornev:

Reg/ No./48,711